



ATTORNEY DOCKET NO.: 02008.071001; AD-0243PCTUS
U.S. PATENT APPLICATION NO.: 09/980,891

PATENT

2829
8/A
2/19/03
Robert
He Amdt

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT(S): MASAHIRO ISHIDA, et al.
APPL/SER. NO.: 09/980,891
FILED: DECEMBER 3, 2001
TITLE: METHOD AND APPARATUS FOR
DEFECT ANALYSIS OF SEMI-
CONDUCTOR INTEGRATED
CIRCUIT

§ **ART UNIT:** 2829
§ **EXAMINER:** T. NGUYEN
§
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Assistant Commissioner for Patents
Washington, DC 20231

PRELIMINARY AMENDMENT

Dear Sir:

Before examining the referenced application on the merits, please amend the
application as outlined below:

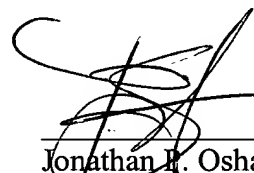
IN THE TITLE:

Please amend the title to read — **Method and Apparatus For Defect Analysis of
Semiconductor Integrated Circuit** —.

Please apply any charges not covered, or any credits, to Deposit Account 50-0591,
reference number 02008.071001.

Dated: 3/7/03

Signature:

 #45,079
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